

AUG. 7. 2007 5:25PM LNAPW 512-439-7199

RECEIVED  
CENTRAL FAX CENTER

NO. 2257 P. 3

AUG 07 2007

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Venkat Selvamanickam, et al.

Title: METALORGANIC CHEMICAL VAPOR DEPOSITION (MOCVD)  
PROCESS AND APPARATUS TO PRODUCE MULTILAYER HIGH-  
TEMPERATURE SUPERCONDUCTING (HTS) COATED TAPE

App. No.: 10/602,468 Filed: June 23, 2003

Examiner: Jennifer C. McNeil Group Art Unit: 1775

Customer No.: 34456 Confirmation No.: 2661

Atty. Dkt. No.: 1014-SP156-US

---

MS AF  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

DECLARATION UNDER 37 C.F.R. §1.132

Sir, I hereby declare and state:

*Considered  
JL 9/27/07*

1. I am a joint inventor of the subject matter presently claimed in the above-identified patent application.
2. I received my doctorate degree in Materials Engineering from the University of Houston in Houston, TX.
3. I have been employed by IGC/SuperPower, Inc. since 1994, wherein I have been mainly engaged in research and development of superconducting materials, superconducting conductors, and processes for forming same.
4. I have reviewed the Office Action dated October 18, 2005, including the positions taken by the PTO with respect to several prior art references. I have also particularly reviewed the subject matter of US 2005/0173679, Mannhart et al. (Mannhart). For the reasons discussed below, Mannhart fails to disclose (or suggest) all features of the claimed invention.